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CMOS vs. CCD sensors in speckle interferometry

Heinz Helmers*, Markus Schellenberg

Institut für Physik, Carl von Ossietzky Universität Oldenburg, PF 2503, D-26111 Oldenburg, Germany

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Abstract

In the field of interferometric metrology the use of high resolution CCD sensors with 1024×1024 to 2048×2048 pixels is predominant. Due to special features (e.g. random pixel access, characteristic curve) CMOS sensors with similar resolution can be an interesting alternative. We compare some characteristics of both sensor types that are important for interferometry and demonstrate two exemplary applications that are only possible by using CMOS cameras. © 2003 Elsevier Ltd. All rights reserved.

Keywords: CCD sensors; CMOS sensors; Speckle interferometry

1. Introduction

in order to realize deformation measurements for an object For some time CMOS cameras have been discussed as with strongly varying reflectivity. In the other case we use an ck ter me lov cal pix reg een pix ies For further information: loc els har ich CC on the of Heinz.Helmers@uni-oldenburg.de noi ıctic T) cha ells to hat FΤ bri 0soi ge) CN ise ov ed CN Sof (E) hot some $\mu v/e$. run-frame-transfer (rr or rr i) sensors

* Corresponding author. Tel.: +49-441-798-3512; fax: +49-441-798-3576.

have separate storage cells. In these sensors the image information after exposure is shifted line by line in a horizontal register and from there pixel by pixel to the sense node.

case we use the nonlinear characteristic curve of the camera

E-mail address: heinz.helmers@uni-oldenburg.de (H. Helmers).